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Investigation on origin of $Z_{1/2}$ center in SiC by deep level transient spectroscopy and electron paramagnetic resonance

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The $Z_{1/2}$ center in n-type 4H-SiC epilayers—a dominant deep level limiting the carrier lifetime—has been investigated. Using capacitance versus voltage (*C*-*V*) measurements and deep level transient spectroscopy (DLTS), we show that the $Z_{1/2}$ center is responsible for the carrier compensation in n-type 4H-SiC epilayers irradiated by low-energy (250 keV) electrons. The concentration of the $Z_{1/2}$ defect obtained by *C*-*V* and DLTS correlates well with that of the carbon vacancy (V_C) determined by electron paramagnetic resonance, suggesting that the $Z_{1/2}$ deep level originates from V_C. © 2013 *American Institute of Physics*. [http://dx.doi.org/10.1063/1.4796141]

SiC is an attractive semiconductor for realizing highpower, high-temperature, and high-frequency devices. Deep levels in semiconductors can act either as carrier traps reducing the conductivity or recombination centers limiting the carrier lifetimes. The $Z_{1/2}$ center^{1–3} is one of the most important deep levels in 4H-SiC, known as a lifetime killer.^{4,5} The origin of the $Z_{1/2}$ center seems to include a carbon vacancy (V_C) because (i) this defect is generated by irradiation with electrons of energy as low as 100 keV,^{6–8} which corresponds to the threshold energy that can displace only carbon atoms in SiC and (ii) a lower $Z_{1/2}$ concentration is observed in SiC epilayers grown under C-rich condition.⁹

Based on the correlation between the energy determined by deep level transient spectroscopy (DLTS) for the $Z_{1/2}$ center and by electron paramagnetic resonance (EPR) for the single negative C vacancy $(V_C(-))$,¹⁰ the $Z_{1/2}$ center has recently been suggested to be the acceptor level of V_C .¹¹ In this paper, we will show the correlation in concentration between the $Z_{1/2}$ defect (obtained by capacitance-voltage (*C-V*) and DLTS) and V_C (determined by EPR) in n-type 4H-SiC irradiated by low-energy (250 keV) electrons with various electron fluences.

A direct comparison of the defect concentration determined by DLTS (or *C-V*) and by EPR is not easy. EPR measurements are suitable for relatively high defect concentrations (>10¹² spins), which require high electron fluences to create. However, materials irradiated with high electron fluences often become highly resistive and are not suitable for DLTS and *C-V* measurements. Therefore, in previous studies, samples used for DLTS were irradiated with much lower electron fluences compared to samples used for EPR measurements.¹² In this study, in order to be able to characterize the same samples in *C-V*, DLTS, and EPR experiments, we chose n-type thick 4H-SiC epilayers with a relatively high N concentration ($N_d \sim 1.6 \times 10^{17} \text{ cm}^{-3}$) so that the materials can still be used for electrical measurements after irradiation with high electron fluences.

The starting materials are n-type 4H-SiC epilayers (thickness: $100 \,\mu\text{m}$, $N_{\rm d}$: $1.6 \times 10^{17} \,\text{cm}^{-3}$). The epilayers were irradiated by 250 keV electrons with different fluences: (A) $7.5 \times 10^{18} \text{ cm}^{-2}$, (B) $7.2 \times 10^{18} \text{ cm}^{-2}$, (C) $5.7 \times 10^{18} \text{ cm}^{-2}$, (D) $4.3 \times 10^{18} \text{ cm}^{-2}$, and (E) $3.1 \times 10^{18} \text{ cm}^{-2}$. Ni/SiC Schottky structures have been made on the samples used for C-V, I-V, and DLTS measurements while the substrate of the other set of samples to be used for EPR was removed by mechanical polishing. For data sampling in all DLTS measurements, a period width of 0.205s and a frequency of 1MHz were employed. In DLTS measurements, the reverse bias voltage was varied in the range of 0-100V, which corresponds to the monitored depth of about 100-800nm in samples A-E. EPR measurements were performed on an X-band (~9.4GHz) Bruker E500 spectrometer equipped with a continuous Heflow cryostat, allowing the sample temperature regulation in the range of 4-295K. In photoexcitation EPR (photo-EPR) experiments, a 200W halogen lamp and appropriate optical filters were used for excitation.

Figure 1(a) shows the C-V characteristics at room temperature (RT) obtained from SiC irradiated with different fluences. The capacitance of samples A-D is very small and almost constant independent of the bias voltage, indicating that these samples have a completely compensated region (CR) caused by electron capture of deep levels (these samples have a very thick depletion region even under 0 V bias). Figure 1(b) shows the dependence of the CR thickness (d_{CR}) on the electron fluence, which was derived from the equation: $d_{\rm CR} = \epsilon/C$, where ϵ the dielectric constant and C the capacitance per unit area obtained from Fig. 1(a). Samples irradiated with a higher fluence show a thicker CR, indicating that deep levels are not uniformly distributed along the depth. Figure 2 shows depth profiles of the $Z_{1/2}$ center in lower doping 4H-SiC epilayers ($N_d \sim 1.6 \times 10^{15} \text{ cm}^{-3}$; initial $Z_{1/2}$ concentration: $1.7 \times 10^{13} \text{ cm}^{-3}$) after 250 keV electron irradiation with various fluences ($3 \times 10^{15} \text{ cm}^{-2}$, $1 \times 10^{16} \text{ cm}^{-2}$, and $2 \times 10^{16} \text{ cm}^{-2}$). Because the CR region is formed where the trap concentration exceeds the doping

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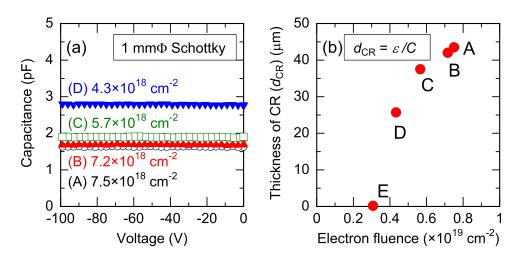


FIG. 1. (a) *C-V* characteristics at RT of samples irradiated by low-energy (250 keV) electrons with various fluences (circles: $7.5 \times 10^{18} \text{ cm}^{-2}$, triangles: $7.2 \times 10^{18} \text{ cm}^{-2}$, squares: $5.7 \times 10^{18} \text{ cm}^{-2}$, reverse triangles: $4.3 \times 10^{18} \text{ cm}^{-2}$). (b) Thickness of the compensated region (d_{CR}) in samples A–E calculated from the constant capacitance shown in Fig. 1(a).

concentration, a higher electron fluence should lead to a thicker d_{CR} as shown in Fig. 1(b).

Figure 3 shows DLTS spectra observed in samples A and E. The spectrum in the lower temperature region of sample A was obtained by current deep level transient spectroscopy (I-DLTS) because the very low capacitance (caused by severe compensation) disturbed capacitance deep level transient spectroscopy (C-DLTS) measurements. At higher temperatures (>400 K), the capacitance recovered to the value before electron irradiation, which enabled C-DLTS measurements of irradiated samples. As shown in Fig. 3, ET1 $(E_{\rm C} - 0.30 \,\text{eV})$,⁷ EH₁ $(E_{\rm C} - 0.34 \,\text{eV})$,¹³ $Z_{1/2} (E_{\rm C} - 0.67 \,\text{eV})$,¹ EH₃ $(E_{\rm C} - 0.72 \,\text{eV})$,¹³ EH₅ $(E_{\rm C})$ -1.2 eV,¹³ ET4 ($E_{\rm C} - 1.3 \text{ eV}$), and EH_{6/7} ($E_{\rm C} - 1.5 \text{ eV}$)¹³ centers were observed in the irradiated samples. The activation energy was derived with assuming a temperature independent capture cross section (σ). Taking into account that the activation energy for σ of $Z_{1/2}$ center (which corresponds to the barrier for capturing the second electron to the $Z_{1/2}$ level) is $0.074\,eV,^{14,15}$ the energy level of $Z_{1/2}$ center is recalculated to be at $\sim E_{\rm C} - 0.59 \, {\rm eV}$. All these deep levels are often observed in irradiated 4H-SiC except for the ET4 center, which is not easy to be separated from the EH_{6/7} center because of severe overlapping. Among these centers, the $Z_{1/2}$ center has the highest

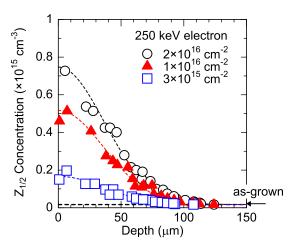


FIG. 2. Depth profiles of the $Z_{1/2}$ center in low-doped 4H-SiC epilayers ($N_d : 1.6 \times 10^{15} \, \text{cm}^{-3}$, initial $Z_{1/2}$ concentration: $1.7 \times 10^{13} \, \text{cm}^{-3}$) after 250-keV-electron irradiation with various fluences (circles: $2 \times 10^{16} \, \text{cm}^{-2}$, triangles: $1 \times 10^{16} \, \text{cm}^{-2}$, squares: $3 \times 10^{15} \, \text{cm}^{-2}$).

concentration although the absolute concentration could not be evaluated due to very high trap concentrations (the $Z_{1/2}$ concentration in sample E is about 1×10^{17} cm⁻³ while N_d is 1.6×10^{17} cm⁻³).

Figure 4 shows the carrier concentration (filled circles) and the Fermi level (circles) in the CR of samples A-E. The carrier concentration n in the CR was roughly estimated from the resistivity ρ in the CR of each sample using the equation: $n = 1/e\rho\mu$. The ρ value was calculated from the series resistance of Schottky barrier diodes (R) obtained from *I*-V measurements using the equation: $\rho = R/d_{CR}$. The electron mobility μ in the CR was assumed to be 370 cm²/Vs using empirical equations given in a paper.¹⁶ For this estimation of μ , an ionized impurity concentration of $3.2 \times 10^{17} \,\mathrm{cm^{-3}}$ was used because there should be ionized donors of $1.6 \times 10^{17} \,\mathrm{cm}^{-3}$ and traps filled with electrons of $1.6 \times 10^{17} \,\mathrm{cm}^{-3}$. The Fermi level E_{F} in the CR can be estimated from the carrier concentration n using the equation: $E_{\rm F} = E_{\rm C} - kT \ln(N_{\rm C}/n)$, and $E_{\rm F}$ is evaluated to be approximately at $E_{\rm C} - 0.53 \, {\rm eV}$ in samples A–D, which is close to the energy level of the $Z_{1/2}$ center as shown in Fig. 4. With the Fermi level located at $E_{\rm C} - 0.53 \, {\rm eV}$, the $Z_{1/2}$ center $(E_{\rm C} - 0.59 \,{\rm eV})$ is occupied with electrons (the occupancy ${\sim}91\%$ at 300 K). Taking into account that $Z_{1/2}$ has the highest concentration (over $1 \times 10^{17} \,\mathrm{cm}^{-3}$) among deep levels observed in these samples, this defect should be the dominant compensating center, creating the CR.

It has been shown that in darkness most of V_C are in the double negative charge state, giving rise to no EPR signal.¹¹ The observation of the EPR signal of $V_{\rm C}(-)$ requires illumination. In all samples, the EPR signal of $V_{\rm C}(-)$ is found to be dominant, suggesting that the acceptor levels of V_C play a key role in the formation of the CR in studied samples. Figure 5 shows the dependence of the area density of $V_{\rm C}(-)$ in the samples A-E obtained by EPR measurements under illumination with light of photon energy smaller than 1.6 eV, and the value $0.1N_{\rm d}d_{\rm CR}$ on the electron fluence. It should be noted here that under illumination, V_C can be in the neutral, single-negative, or double-negative charge state.¹¹ The $V_{\rm C}(-)$ volume density should be limited by $N_{\rm d}$ because an electron is needed for V_C to become $V_C(-)$. The value $N_{\rm d} d_{\rm CR}$ corresponds to the maximum value of the V_C(-) area density under an assumption that almost all $V_{C}(-)$ signal comes from the CR. The assumption is reasonable because

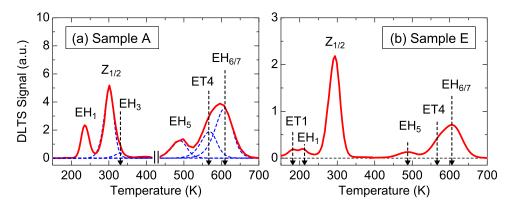


FIG. 3. DLTS spectra observed in samples (a) A (electron fluence: $7.5 \times 10^{18} \text{ cm}^{-2}$) and (b) E (electron fluence: $3.1 \times 10^{18} \text{ cm}^{-2}$). The lower temperature region of the spectrum in sample A was obtained by I-DLTS.

the V_C density in the CR is much higher than that in the tail uncompensated region, and most of V_C in the tail region should be in the double-negative (2–) charge state since the concentration of V_C is lower than that of donor concentration and the Fermi level is near the N shallow donor. As shown in Fig. 5, 10% of $N_d d_{CR}$ shows a good agreement with the

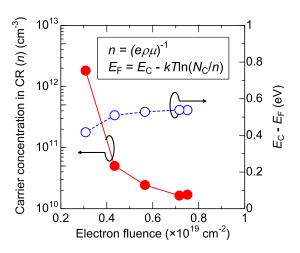


FIG. 4. The dependence on the electron fluence of the carrier concentration n and the Fermi level at 300 K in the CR in samples A–E. Here, n was estimated from the resistivity ρ in the CR for each sample.

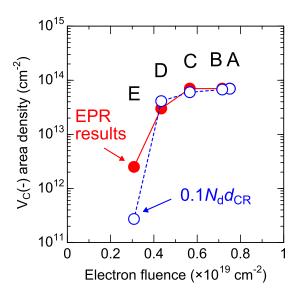


FIG. 5. Electron fluence dependence of the area density of carbon vacancy in the single-negative charge state (V_C(-)) in samples A–E obtained by EPR measurements under illumination with light of photon energy smaller than 1.6 eV, and the 0.1 $N_d d_{CR}$ value. $N_d d_{CR}$ corresponds to the maximum V_C(-) area density.

V_C(-) area density obtained by EPR measurements, indicating that under illumination at 100 K, about 10% of electrons in the CR exists as $V_{C}(-)$, while most of the other electrons may do as $V_{\rm C}(2-)$. Note that the calculated value $0.1 N_{\rm d} d_{\rm CR}$ in the sample E is considerably smaller than the $V_{C}(-)$ area density obtained by EPR. Although the assumption that the EPR signal of $V_{\rm C}(-)$ comes mainly from the CR is reasonable for samples A-D with thick CR, it is not valid for sample E, which has a very thin CR and the amount of V_C in the uncompensated region cannot be neglected compared to that in the very thin CR ($\sim 0.17 \,\mu m$). Neglecting the contribution of V_C in the uncompensated region leads to the underestimation of the value $N_{\rm d} d_{\rm CR}$ in sample E. These EPR results with V_C having the highest density among all defects in the samples A-E and the $V_C(-)$ density following the maximum value of $V_{\rm C}(-)$ density limited by $N_{\rm d}$ indicate that $V_{\rm C}$ is the dominant defect creating the CR.

Comparing the data obtained from DLTS, *C-V*, and EPR measurements, it is clear that (i) the dominant deep level in samples A–E is the $Z_{1/2}$ center and the dominant point defect is V_C and (ii) the compensation in irradiated samples is caused by electron capture to the $Z_{1/2}$ center (as shown from DLTS) and to the acceptor levels of V_C (as shown in EPR). Thus, the $Z_{1/2}$ center, which capture two electrons as known from DLTS, ¹⁴ should be related to the double negative charge state of V_C (it is known that the EH₇ DLTS level and

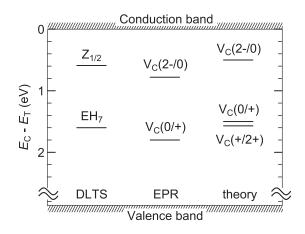


FIG. 6. Overview of the activation energy of deep levels obtained by DLTS (in this paper) and the energy of the (2-/0) and (0/+) levels of V_C determined by photo-EPR (Ref. 11) with respect to the conduction band minimum. The optical transitions determined by EPR involve a possible Franck-Condon shift, which has to be taken into account to be compared with the activation energy determined by DLTS. The energy levels of V_C in different charge states obtained by *ab initio* calculation (Ref. 18) are also shown for comparison.

the $Z_{1/2}$ center originate from the same defect,^{7,17} and EH₇ is related to the (0/+) charge state of V_C (Ref. 11)).

Figure 6 shows the activation energy (E_{act}) of deep levels obtained by DLTS and the optical transition levels related to V_C levels (E_{exc}) determined by photo-EPR¹¹ with respect to the conduction band edge $(E_C = 0)$. To compare E_{exc} with E_{act} , a possible Franck-Condon shift involved in the optical transitions has to be taken into account $(E_{act} = E_{exc} - E_{FC})$. The activation energy of V_C obtained by *ab initio* calculations¹⁸ are also shown in Fig. 6, which agrees well with the energy levels obtained by DLTS and EPR measurements.

In summary, using n-type 4H-SiC epitaxial layers irradiated by low-energy (250 keV) electrons, which can mainly create defects in the C sub-lattice (V_C, C interstitials and their associated defects) with different fluences, we were able to employ different techniques (*C-V*, DLTS, and EPR) to study the $Z_{1/2}$ and V_C defects in the same samples. It has been shown that $Z_{1/2}$ and V_C are the dominant defects responsible for the carrier compensation observed in the irradiated samples, suggesting that the $Z_{1/2}$ center originates from a C vacancy and is related to the EPR inactive 2– charge state of V_C.

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